

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

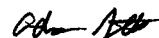
Applicant : Basol et al.
Appl. No. : 10/654,542
Filed : September 2, 2003
For : CONSTANT LOW FORCE
WAFER CARRIER FOR
ELECTROCHEMICAL
MECHANICAL PROCESSING
AND CHEMICAL MECHANICAL
POLISHING
Examiner : Eileen P. Morgan
Group Art Unit : 3723
Confirmation No. : 3972

**CERTIFICATE OF EFS WEB
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I hereby certify that this correspondence, and any other attachment noted on the automated Acknowledgement Receipt, is being transmitted from within the Pacific Time zone to the Commissioner for Patents via the EFS Web server on:

August 15, 2007

(Date)



Adam Gilbert, Reg. No. 59,967

**SUPPLEMENTARY AMENDMENT IN RESPONSE TO NOTICE OF
NON-COMPLIANT AMENDMENT DATED AUGUST 3, 2007****Mail Stop Amendment**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Madam:

Prior to the continued examination of the above-captioned application, please amend the application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 5 of this paper.